

Title (en)

Lithographic projection apparatus and device manufacturing method

Title (de)

Lithographischer Projektionsapparat und Verfahren zur Herstellung einer Vorrichtung

Title (fr)

Appareil de projection lithographique et méthode de fabrication d'un dispositif

Publication

**EP 0950924 A2 19991020 (EN)**

Application

**EP 99302740 A 19990408**

Priority

- EP 99302740 A 19990408
- EP 98201172 A 19980414

Abstract (en)

A lithographic apparatus of the scanning type in which reticle masking blades 7 are opened at the beginning of a scan. Means are provided to compensate for an increase in the intensity density of the illumination beam as the reticle masking blades are opened. These means may comprise lamp control means 10 for controlling a compensating decrease in the lamp intensity. The reticle masking blades 70 may be manufactured of, e.g., quartz and provided with a reflective rear coating, e.g. of aluminium, so that portions of the illumination beam intercepted by the reticle masking blades are totally internally reflected. <IMAGE>

IPC 1-7

**G03F 7/20**

IPC 8 full level

**G03F 7/20** (2006.01)

CPC (source: EP)

**G03F 7/70066** (2013.01); **G03F 7/70358** (2013.01); **G03F 7/70558** (2013.01)

Cited by

DE10116060B4; DE10116058B4; CN1302340C; US6803991B2; US7384709B2; US7445873B2; US10007193B2; US7413830B2; WO2013185919A1; WO02084405A1; WO02084404A1

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